

Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)							ATTY. DOCKET NO. 2925-0329P	APPLICATION NO. NEW			
							APPLICANT Sungho JIN et al.				
							FILING DATE June 23, 1999	GROUP Unassigned			
U.S. PATENT DOCUMENTS											
EXAMINER INITIAL	DOCUMENT NUMBER						DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
TSC	5	4	2	6	6	8	6	1995-06-20	Rentzepis et al.		
FOREIGN PATENT DOCUMENTS											
	DOCUMENT NUMBER						DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION
										YES	NO
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)											
TSC		W. DeVore et al., "High emittance electron gun for projection lithography", 1998 American Vacuum Society, J. Vac. Sci. Technol. B14(6), Nov./Dec., 1996, pp. 3764-3769									
TSC		W.K. Waskiewicz et al., "Design of a Low-Brightness, Highly Uniform Source for Projection Electron-Beam Lithography (SCALPEL)", Proc. SPIE, 3155, 1997									
TSC		J. Hasker et al., "Cathode and Scaling Properties Related to the Shape of Current-Voltage Characteristics", Applied Surface Science 24 (1985), pp. 318-329									
TSC		Robert Bakish, "Introduction to Electron Beam Technology", pp. 73-74									
EXAMINER <i>Thelma Sheree Clore</i>		DATE CONSIDERED <i>7-31-01</i>									
EXAMINER initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.											